WHAT IS CLAIMED IS:

1. An inspecting apparatus which comprises: a signal supply device for supplying signals to a thin-film transistor active matrix substrate for an organic EL panel; a probe positioned facing the substrate; a detector for detecting signals flowing to the probe; and a fluid supply device for supplying a dielectric fluid between the substrate and the probe.

2. The inspecting apparatus according to claim 1, wherein said signal supply device supplies non-standing wave signals.

3. The inspecting apparatus according to claim 1, wherein said dielectric fluid is a liquid comprised of polar molecules.

4. The inspecting apparatus according to claim 3, wherein said dielectric fluid is water.

5. The inspecting apparatus according to claim 1, wherein said probe has a plurality of electrodes for inspecting.

6. The inspecting apparatus according to claim 1, wherein said detector detects a current flowing to the probe.

7. A method for inspecting thin-film transistor active matrix substrates which comprises: bringing a probe opposite a thin-film transistor active matrix substrate for an organic EL panel; introducing a dielectric fluid between the substrate and the probe; supplying signals to a closed circuit consisting of the substrate, the dielectric fluid, and the probe; and detecting signals flowing to the closed circuit.

8. The method according to claim 7, wherein a detecting surface area of the probe is wider than the surface area of a pixel on the substrate.

9. A method for inspecting thin film transistor active matrix substrates which comprises: bringing a probe opposite a thin-film transistor active matrix substrate; introducing a dielectric fluid between the substrate and the probe; forming an air or nitrogen flow at the end face of the probe; discharging the dielectric fluid from between the end face of the probe and the air flow; supplying signals to a closed circuit consisting of the substrate, dielectric fluid, and probe; and detecting the signals flowing to the closed circuit.

10. A method for inspecting thin-film transistor active matrix substrates which comprises: bringing a probe opposite a thin-film transistor active matrix substrate; introducing a dielectric fluid between the substrate and the probe; supplying signals to a closed circuit consisting of the substrate, the dielectric fluid, and the probe; and detecting signals flowing to the closed circuit, wherein

the distance between the substrate and the probe is controlled by the amount of dielectric fluid that is introduced.